

300mm Semi-Automatic Vacuum Mounter

RAD-2512m/12



Facility

Power Supply	Voltage	: AC200-230V±10% (AC190-253V)
	Frequency	: 50/60Hz
	Phase	: Single phase
Air Supply	Power consumption	: 15kW
	Air pressure	: 0.6-0.8MPa
	Air consumption	: <100L/min (ANR)
Vacuum Supply (for vacuum chamber)	Ultimate Pressure	: 1.0Pa
	Pumping Speed	: >250L/min

Applicable Wafer Size 150mm, 200mm, 300mm(Warpage: >2mm)

Size
Width(W) : 1,100mm
Depth(D) : 660mm(excluding protruding parts)
Height(H) : 1,098mm
(When upper chamber is fully open)

Weight 400kg

UPH 60sec/wafer (excludes setting time)

The above processing capacity is based on following conditions:

Wafer : 200mm non-polished mirror wafer

Outline

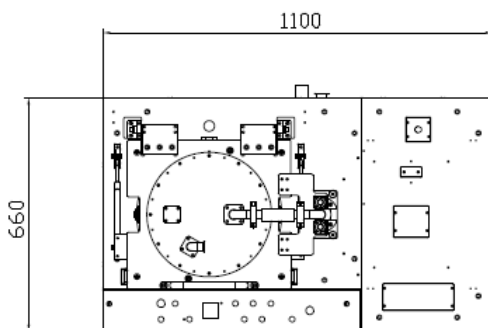
- Semi-automatic vacuum mounter that can mount a wafer to a pre-cut dicing tape mounted on a ring frame. This process is performed under a vacuum atmosphere.
- By using our unique vacuum control method, wafer mounting is performed without any contact to the wafer surface.
- By using our unique differential pressure control mechanism, excellent conformity to stepped surfaces is achieved.

Options · Heater Table

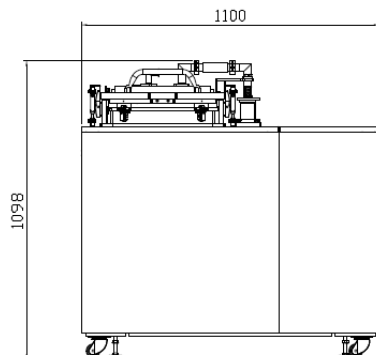
Suitable Tape · Dicing Tape: Adwill D Series, G Series

External View

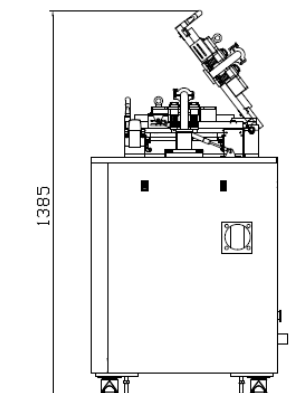
Unit:mm



Top View



Front View



Right Side View

